

FIG. 1A

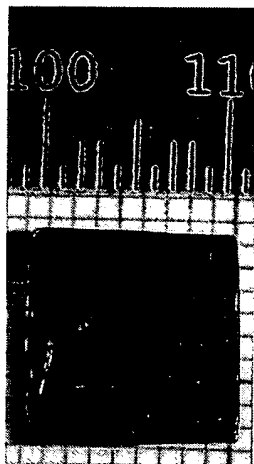


FIG. 1B

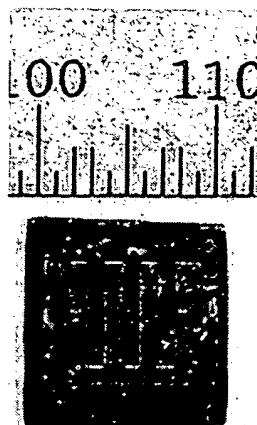


FIG. 1C

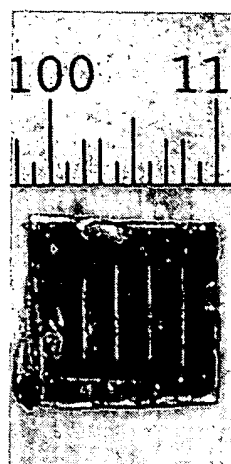


FIG. 1D

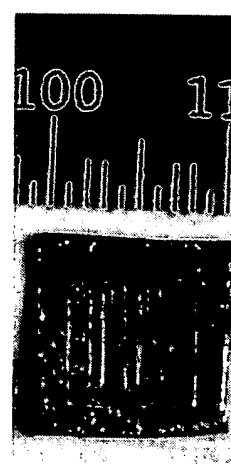


FIG. 1E

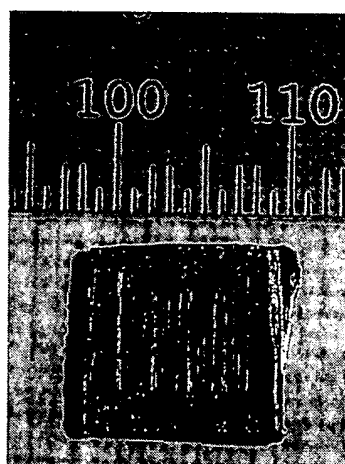


FIG. 1A-1E

Mercuric iodide after various processing steps: (1A) lithography on Pd to define grid etch pit. (1B) etching of Pd. (1C) HgI₂ sublimation etch (300 μm). (1D) lithography for grid and collecting electrodes. (1E) after Pd etching.

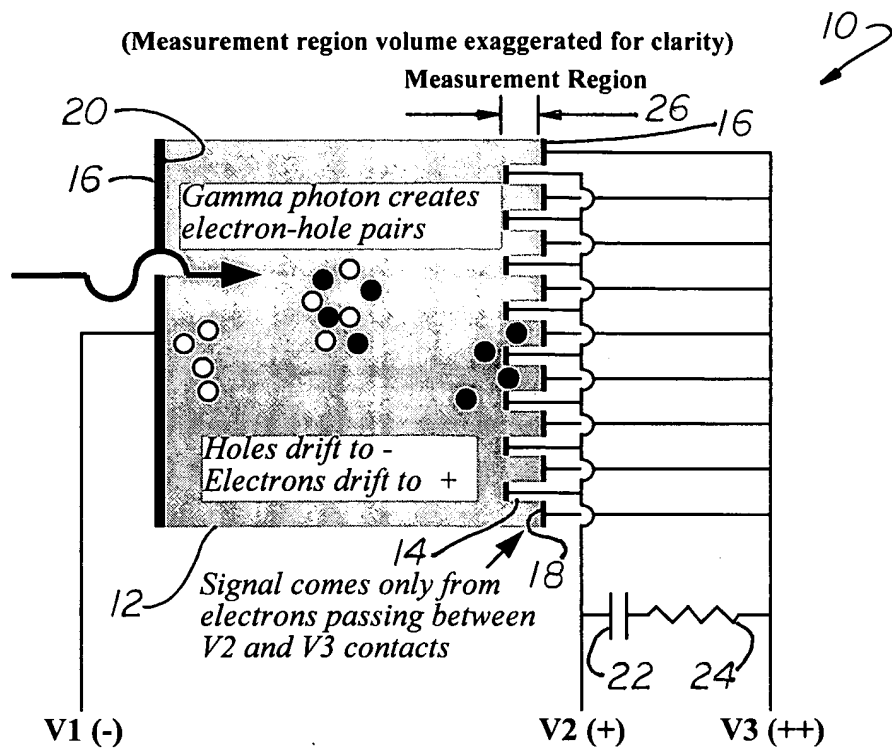


FIG. 2